

566.39787CX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

T. UCHIDA et al.

Serial No.:

09/976,001

Filed:

October 15, 2001

For:

ABRASIVE LIQUID FOR METAL AND METHOD OF POLISHING

Group:

1765

Examiner:

Lynette T. Umez Eronini

UNDER 37 CFR §§1.97 AND 1.98

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

June 30, 2004

Sir:

Pursuant to Applicants' duty to disclosure, enclosed please find a copy of an Office Action issued by the Korean Patent Office in connection with a Korean Patent Application corresponding to the above-identified application. Also enclosed are copies of documents cited in this Office Action issued by the Korean Patent Office. Further enclosed is an English language abstract of Japanese Patent Document No. 08-083780; and a copy of International (PCT) Publication No. WO 00/00561. Please note that Japanese Patent Document No. 08-083780 was one of the two documents cited in the aforementioned Office Action from the Korean Patent Office, and the enclosed International Patent Publication corresponds to Korean Patent

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Publication No. 2001-0053167, the other publication cited in the aforementioned Office Action from the Korean Patent Office.

Note that in connection with Japanese Patent Document No. 08-083780 and Korean Patent Document No. 2001-0053167, requirements of 37 C.F.R. §1.98(a)(3) are satisfied by the English language abstract of the Japanese Patent Document and by the corresponding International Published Application, respectively.

Also enclosed is a Form, substantially equivalent to Form PTO-1449, listing the documents cited in the aforementioned Office Action from the Korean Patent Office, and corresponding English language documents.

Also on the enclosed Form are listed documents cited in connection with office actions mailed January 5, 2004, and May 7, 2003, in prior Application No. 09/763,891, being relied upon under 35 U.S.C. §120 in the above-identified application, with the exception that documents cited in either of these office actions in No. 09/763,891, that have previously been cited in the above-identified application, are not set forth on the enclosed Form. Since No. 09/763,891 is being relied upon under 35 U.S.C. §120 in the above-identified application, copies of the documents listed on the enclosed Form, cited in the aforementioned office actions in No. 09/763,891, are not enclosed. See 37 C.F.R. §1.98(d).

This Information Disclosure Statement is being submitted subsequent to a first office action on the merits after filing a Request For Continued Examination Under 37 C.F.R. §1.114; and in an application that is <u>not</u> under a final rejection, and wherein a Notice of Allowance has not been issued under 37 C.F.R. §1.311, and no action that otherwise closes prosecution on the merits in the application has been

Appl. No. 09/976,001 Information Disclosure Statement dated June 30, 2004

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issued therein. For satisfying requirements of 37 C.F.R. §1.97(c), the fee set forth in 37 C.F.R. §1.17(p) is enclosed.

In view of all of the foregoing, it is respectfully submitted that all applicable requirements of 37 C.F.R. §§1.97 and 1.98 have been satisfied, in connection with all documents listed on the enclosed Form. Accordingly, consideration of each of the listed documents, upon further examination of the above-identified application, is respectfully requested.

Please charge any shortage of fees due in connection with the filing of this paper, including extension of time fees, to the Deposit Account of Antonelli, Terry, Stout & Kraus, No. 01-2135 (Application No. 566.39787CX1), and please credit any excess fees to said deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP

By

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Approved for use through 10/31/2002. OMB 0651-0031

U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

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Complete if Known bstitute for form 1449A/PTO 09/976,001 Application Number INFORMATION DISCLOSURE Filing Date October 15, 2001 STATEMENT BY APPLICANT First Named Inventor T. UCHIDA et al. 1765 Art Unit Lynette T. Umez Eronini Examiner Name (use as many sheets as necessary) Attorney Docket Number 566.39787CX1 of 1 1

	Cite No.1	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where	
Examiner Initials'		Number-Kind Code ² (if known)			Relevant Passages or Relevant Figures Appear	
		US- 4.537.654	08-1985	BERENZ et al.		
		US- 4,968,381	11-1990	PRIGGE et al.		
		US- 5,434,107	07-1995	PARANJPE		
		US- 5,691,219	11-1997	KAWAKUBO et al.		
		US- 5,770,103	06-1998	WANG et al.		
		US- 5,876,490	03-1999	RONAY		
		US- 5,954,997	09-1999	KAUFMAN et al.		
		US- 5,981,394	11-1999	OHASHI et al.		
		US- 6,206,756-B1	03-2001	CHOPRA et al.		
		US-				
		US-				
		US-				

	FOREIGN PATENT DOCUMENTS						
Examiner	Cite	Foreign Patent Document	Publication Date	Name of Patentee or	Pages, Columns, Lines, Where Relevant Passages		
Initials'	No. ¹	Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	MM-DD-YYYY	Applicant of Cited Document	or Relevant Figures Appear	T ⁸	
		JP 08-083780	03-26-1996	TOSHIDA CORP		ABS	
		KR 2001-0053167	06-25-2001				
		WO 00/00561	01-06-2000	CABOT CORPORATION			
						$oxed{oxed}$	

OTHER PRIOR ART—NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Τ²		
		Y. HAYASHI et al., "A New Abrasive-Free, Chemical-Mechanical-Polishing for Aluminum Metallization of ULSI Devices", International Electron Devices Meeting Technical Digest, 1992, pp. 976-978			
		LUO et al., Chemical-Mechanical Polishing of Copper in Acidic Media, February 22-23, 1996, 1996 CMP-MIC Conference 1996 ISMIC – 100P/96/0145, pages 145-151.			

Examiner	Date
Signature	Considered

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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¹Applicant's unique citation designation number (optional). ²See Kinds Codes of USPTO Patent Documents at www.uspto.gox or MPEP 901.04. ³Enter Office that issued the document, by the two-letter code (WIPO Standard St.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁵Applicant is to place a check mark here if English language Translation is attached.